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**BOX AF**

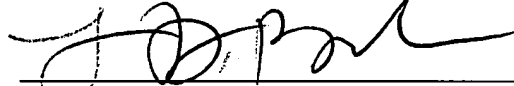
AF  
IFW



PATENT  
RESPONSE UNDER 37 CFR 1.116  
EXPEDITED PROCEDURE  
EXAMINING GROUP 1765

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

*I hereby certify that this correspondence is being deposited with the U.S. Postal Service as first class mail in an envelope addressed to Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on August 3, 2004.*

  
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Lisa D. Bronk

Appl No. : 10/090,915 Confirmation No. 7688  
Applicant : Konstantin Holdermann  
Filed : March 5, 2002  
Title : ETCHING SOLUTION FOR WET CHEMICAL PYRAMIDAL TEXTURE  
ETCHING OF SILICON SURFACES  
  
TC/A.U. : 1765  
Examiner : Shamim Ahmed  
  
Docket No. : 47585/RAG/S969  
  
Customer No. : 23363

**RESPONSE AFTER FINAL ACTION**

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450  
  
Post Office Box 7068  
Pasadena, CA 91109-7068  
August 3, 2004  
  
Commissioner:

In response to the Office action of May 4, 2004, please consider the following remarks.

**REMARKS/ARGUMENTS**

As a preliminary matter, applicant would like to thank the Examiner for taking the time to conduct a telephonic interview with applicant's representative on July 14, 2004. During that interview, the Bailey (U.S. Patent No. 4,137,123) and Uchimura (U.S. Patent No. 5,165,957) references were discussed, as well